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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re PATENT application of: CM

Ohtani et al.

10/20/00

Serial No. 08/807,737

Filed: February 27, 1997

For: METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE



) Art Unit: 2822

) Examiner: Evan T. PERT

Certificate of Mailing

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Susan J. Stiles

**AMENDMENT**

Honorable Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated June 22, 2000, please amend the above-identified application and consider Applicant's remark as follows.

**IN THE SPECIFICATION:**

Please amend the specification as follows:

On page 6, line 17, after "absence of" insert -- a--.

On page 28, line 26, change "rational speed" to -- rotational speed--.

**IN THE CLAIMS:**

Please amend the Claims 36 and 74 as follows:

36. (Amended) A method of manufacturing a semiconductor device comprising the steps of:

H1  
cont'd